IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re the Application of

Takeshi KIJIMA et al.

Application No.:

10/724,635

Filed: December 2, 2003

Docket No.: 117926

For:

METHOD OF MANUFACTURING OXIDE THIN FILM, METHOD OF

MANUFACTURING FERROELECTRIC THIN FILM, FERROELECTRIC THIN FILM, FERROELECTRIC MEMORY DEVICE, AND FERROELECTRIC PIEZOELECTRIC

DEVICE

INFORMATION DISCLOSURE STATEMENT

Commissioner for Patents P.O. Box 1450 Alexandria, VA 22313-1450

Sir:

Pursuant to 37 CFR §1.56, the attention of the Patent and Trademark Office is hereby directed to the reference listed on the attached PTO-1449. Unless otherwise indicated herein, one copy of each reference is attached. It is respectfully requested that the information be expressly considered during the prosecution of this application, and that the reference be made of record therein and appear among the "References Cited" on any patent to issue therefrom.

- 1. This Information Disclosure Statement is being filed (a) within three months of the U.S. filing date of this non-CPA application, OR (b) before the mailing date of a first Office Action on the merits in the present application. No certification or fee is required.
- 2. An English-language Abstract of the non-English language reference 1 is attached hereto.
- 3. A computer-generated English translation of the following Japanese reference(s) has been obtained from the website of the Japanese Patent Office ([http://www.jpo.go.jp]), and is attached, but has not been reviewed for accuracy. See Reference 1.

Respectfully submitted,

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Date: June 28, 2004

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Form PTO-ATTY DOCKET NO. APPLICATION NO. US Dept. of Commerce 10/724,635 (REV. 8-83) PATENT & TRADEMARK OFFICE 117926 INFORMATION DISCLOSURE STATEMENT (Use several sheets if necessary) APPLICANTS Takeshi KIJIMA et al. FILING DATE December 2, 2003 ' U.S. PATENT DOCUMENTS SUB **EXAMINER** NAME **CLASS CLASS** DATE INITIAL DOCUMENT NUMBER FOREIGN PATENT DOCUMENTS SUB CLASS **CLASS** COUNTRY DOCUMENT NUMBER DATE JP A 2003-213425 w/Abstract & 07/30/2003 Japan Translation OTHER DOCUMENTS (Including Author, Title, Date, Pertinent Pages, etc.)

EXAMINER DATE CONSIDERED

Examiner: Initial if citation considered, whether or not citation is in conformance with M.P.E.P. 609; draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.

Date: June 28, 2004